

Docket No.: 60188-632

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In re Application of | : | Customer Number: 20277 |
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| Wataru ITOH, et al. | : | Confirmation Number: |
| | : | |
| Serial No.: | : | Group Art Unit: |
| | : | |
| Filed: August 11, 2003 | : | Examiner: |
| | : | |
| For: ASSEMBLY FOR LSI TEST AND METHOD FOR THE TEST | : | |

INFORMATION DISCLOSURE STATEMENT

Mail Stop IDS
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

The relevance of two of the references listed on attached Form 1449 is discussed in the present specification.

Serial No.:

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

MCDERMOTT, WILL & EMERY



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Date: August 11, 2003

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| INFORMATION DISCLOSURE CITATION IN AN APPLICATION | | | | ATTY. DOCKET NO. 60188-632 | | SERIAL NO. | |
| (PTO-1449) | | | | APPLICANT Wataru ITOH, et al. | | | |
| | | | | FILING DATE August 11, 2003 | | GROUP | |
| U.S. PATENT DOCUMENTS | | | | | | | |
| EXAMINER'S INITIALS | CITE NO. | Document Number <small>Number-Kind Code² (if known)</small> | Publication Date <small>MM-DD-YYYY</small> | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear | | |
| | | US 4,912,395 | 03/27/1990 | Sato et al. | | | |
| | | US 4,710,930 | 12/1/1987 | Hatayama et al. | | | |
| | | US 4,760,335 | 07/26/1988 | Lindberg | | | |
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| FOREIGN PATENT DOCUMENTS | | | | | | | |
| EXAMINER'S INITIALS | CITE NO. | Foreign Patent Document <small>Country Code³-Number 4 -Kind Codes (if known)</small> | Publication Date <small>MM-DD-YYYY</small> | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines Where Relevant Figures Appear | Translation | |
| | | | | | | Yes | No |
| | | JP 07-128405 | 05/19/1995 | HITACHI LTD | | Japan (w/ English Abstract) | |
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| OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| EXAMINER'S INITIALS | CITE NO. | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | | | | | |
| | | Tomoyuki Hamasuna, "MAJOR PROBLEMS AND SOLUTIONS OF THE SYSTEM LSI TESTING", SEMI Technology Symposium 2001, Semiconductor Equipment and Materials International, December 5-7, 2001 | | | | | |
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| EXAMINER | | | | DATE CONSIDERED | | | |

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.